GP 1765





UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT:

BRUNNER ET AL 1

SERIAL NO:

09/425,694

FILED:

OCTOBER 22, 1999

GROUP:

1765

TITLE:

PROCESS FOR THE WET CHEMICAL TREATMENT OF

SEMICONDUCTOR WAFERS

SUBMISSION OF SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT OF DR. WOLFGANG STAUDACHER

ATT: BOX NON FEE AMENDMENT

Assistant Commissioner for Patents

Washington, D.C. 20231

JAN 28 °C 1700 MA

Dear Sir:

Applicants wish to bring to the attention of the Patents Examiner the attached Information Disclosure Statement, Guly signed by Dr. Wolfgang Staudacher and the nine (9) references listed on the enclosed Form PTO-1449 and attached thereto.

The relevance of these references is that they are cited in the attached European Search report and may be material to the examination of the application.

Since this Information Disclosure Statement is being filed prior to a first Office Action, it is believed that no fee is due. However, if it is determined that a fee is due, the Commissioner is hereby authorized to charge, or to credit any

over payment, to our Deposit Account Number 03-2468.

It is respectfully requested that this Information Disclosure Statement be considered and placed into the application file.



Respectfully submitted,

ROLAND BRUNNER ET AL 1

Allison C. Collard Reg. No. Edward R. Freedman Attorneys for Applicants

COLLARD & ROE, P.C. 1077 Northern Boulevard Roslyn, New York 11576 (516) 365-9802

Enclosures:

Jan.

- Information Disclosure Statement Of Dr. 1) Wolfgang Staudacher
- PTO-form 1449 w/copies of 9 references
- Copy of European Search report 2) 3)

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: ASSISTANT COMMISSIONER OF PATENTS, Washington, D. (20231, of JANUARY 19, 2000.

Ingrid Mittendorf

TC 1700 MAIL ROOM

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of BRUNNER ET AL - 1
Serial Number 09/425,694
Filed: October 22, 1999
For: PROCESS FOR THE WET CHEMICAL TREATMENT OF SEMI-CONDUCTOR WAFERS

Group Art Unit 265

Information Disclosure Statemen

Honorable Commissioner of Patents and Trademarks Washington, D.C. 20231

Sir or Madam:

I, Wolfgang Staudacher, associated with the preparation and prosecution of the above-identified application, residing at Seebauerstraße 4, 81735 München, Germany, wish to call the attention of the Patent Examiner to the references enumerated on the enclosed PTO Form-1449.

I believe the documents enumerated on the enclosed Form PTO-1449 and attached thereto, are cited in the European Search Report and may be material to the examination of the application.

Therefore, it is respectfully requested that the foregoing Information Disclosure Statement be considered by the Examiner and incorporated into the file of this application.

I wish to comment as follows concerning the prior art references enumerated on PTO Form-1449:

For EP 0 731 495 A2 the English Derwent Abstract AN 1996-404246 [41] is enclosed.

EP 0 859 404 A2 is already in English language.

EP 0 731 498 A2 is already in English language.

EP 0 844 650 A2 is already in English language.

PATENT ABSTRACTS OF JAPAN, vol. 1996, no. 06, (1996-06-28) & JP 08 031837 A (MITSUBISHI MATERILAS SHILICON CORP; OTERS: 01) (1996-02-02).

US 5,803,980 is already in English language.

MEURIS M ET AL: "THE IMEC CLEAN: A NEW CONCEPT FOR PARTICLE AND METAL REMOVAL ON SI SURFACES"

SOLID STATE TECHNOLOGY, US, COWAN PUBL. CORP. WASHINGTON, vol. 38, no. 7, 1995, p. 109-110, 112, 114 XP000523398 ISSN: 0038-111X p. 110, l. 5 – l. 44

Signed this T day of January, 2000.

JAN 2 4 2000 PER TRADEMENT

Dr. Wolfgang Staudacher

J411 28 2000 TC 1700 HAIL ROOM